

Study of Ga₂O₃ thin films homoepitaxially grown on (010), (-201), and (001) substrates.

V. SALLET¹, G. AMIRI¹, S. HASSANI¹, C. SARTEL¹, Z. CHI¹, J.M. CHAUVEAU¹, E. CHIKOIDZE¹.

¹ : Université Paris Saclay, UVSQ, CNRS, GEMaC, 45 avenue des Etats Unis, 78000 Versailles, France

SAFEPOWER project



HORIZON-CL5-2024-D3-01

**Safer and More Reliable
WBG/UWBG-based MVDC
Power Converters**



developed thanks to these key enabling technologies:

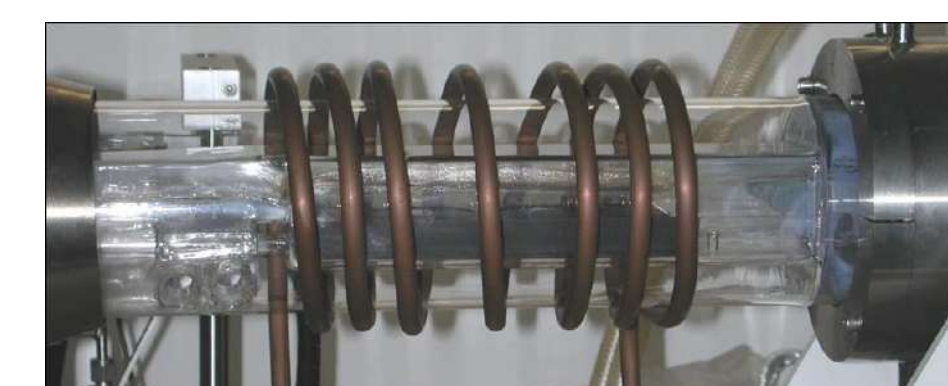
- More efficient and reliable 3.3 kV **Silicon Carbide**-based power devices
- **6.6 kV Gallium Oxide**-based Power Devices
- Disruptive techniques for **electro-thermal power devices** analysis
- **AI-assisted converter** condition & health monitoring
- New **control strategies/architectures** for multilevel conversion

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Experimental

β -Ga₂O₃ epilayers were grown on (010), (-201), and (001) oriented Ga₂O₃ substrates, and R- and C- sapphire substrates by Metal-Organic Vapor Phase Epitaxy (MOVPE).

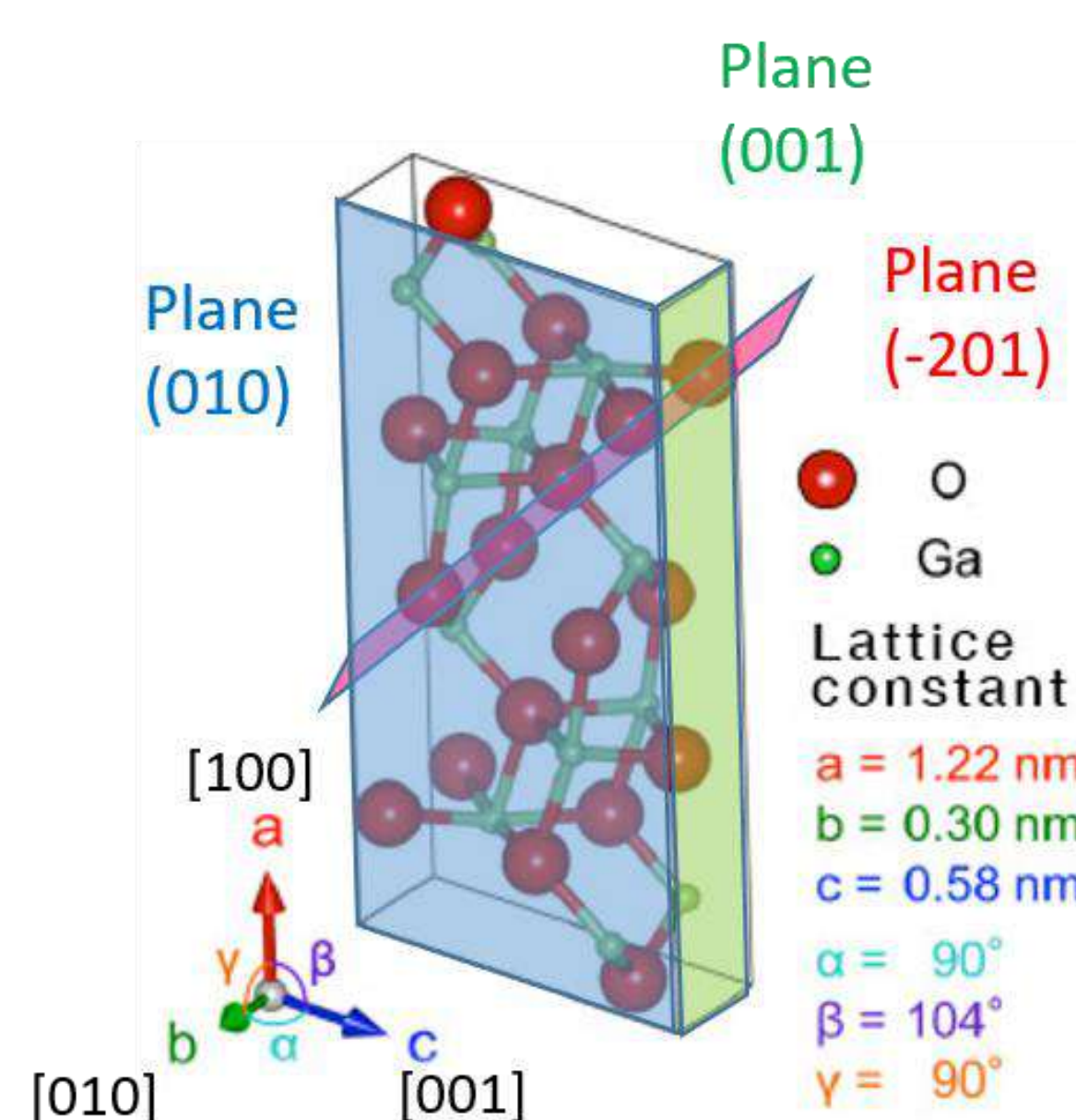


Horizontal reactor

MR Semicon MOVPE system
Low pressure 40 torr, argon, nitrogen or helium carrier gas
Growth temperature ~775°C
Precursors : Trimethylgallium (TMGa), O₂

β -Ga₂O₃ structure

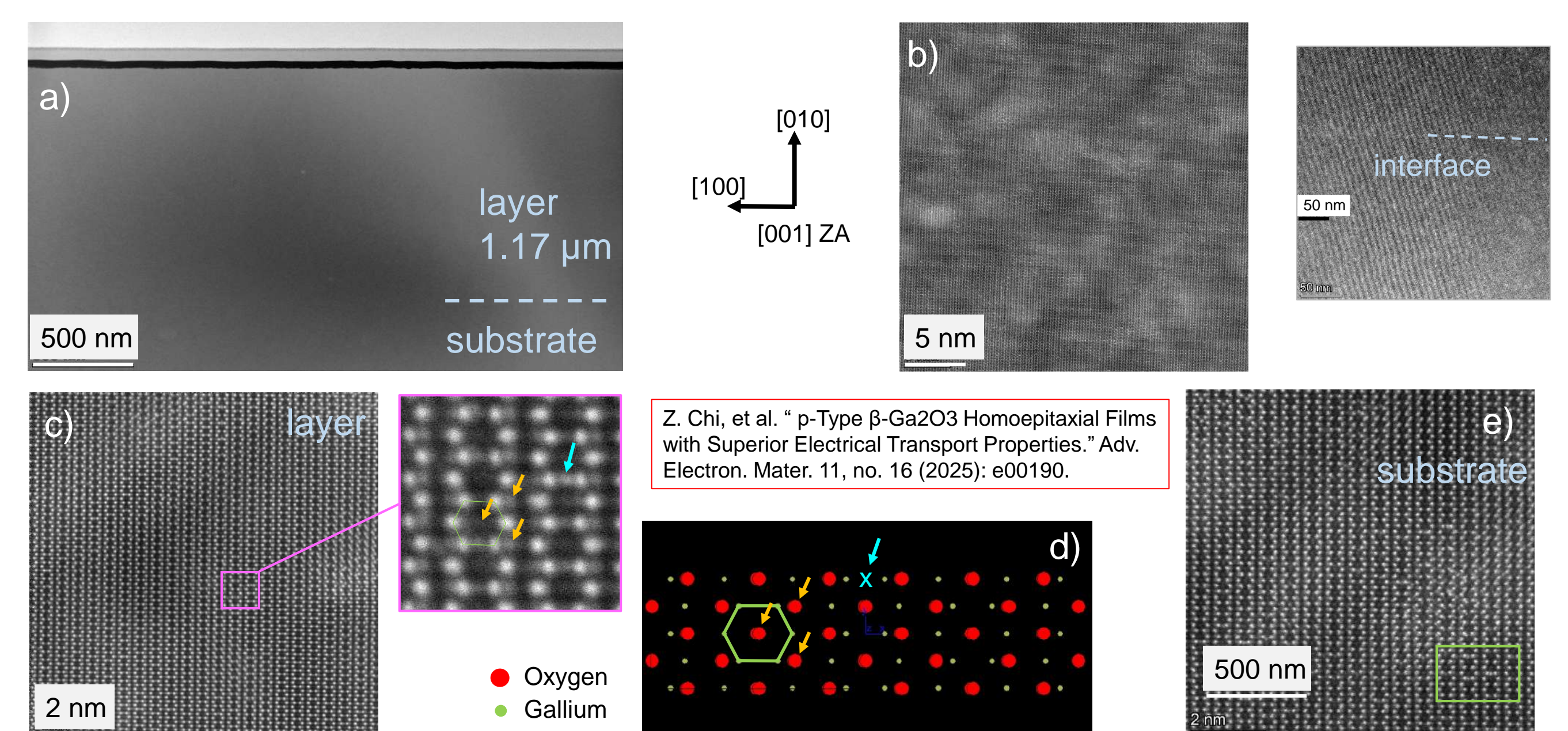
Wide bandgap semiconductor
suitable for power electronics



Materials parameters	Si	GaAs	4H-SiC	GaN	Diamond	β -Ga ₂ O ₃
Bandgap, E _g (eV)	1.1	1.43	3.25	3.4	5.5	4.85
Dielectric constant, ϵ	11.8	12.9	9.7	9	5.5	10
Breakdown field, E _C (MV/cm)	0.3	0.4	2.5	3.3	10	8
Electron mobility, μ (cm ² /Vs)	1480	8400	1000	1250	2000	300
Saturation velocity, v _s (10 ⁷ cm/s)	1	1.2	2	2.5	1	1.8-2
Thermal conductivity λ (W/cm K)	1.5	0.5	4.9	2.3	20	0.1-0.3
Figures of merit relative to Si						
Johnson = E _C ² · V _s ² / 4π ²	1	1.8	278	1089	1110	2844
Baliga = $\epsilon \cdot \mu \cdot E_C^3$	1	14.7	317	846	24 660	3214
Combined = $\lambda \cdot \epsilon \cdot \mu \cdot V_s \cdot E_C^2$	1	3.7	248.6	353.8	9331	37
Baliga high frequency = $\mu \cdot E_C^2$	1	10.1	46.3	100.8	1501	142.2
Keyes = $\lambda \cdot [(c \cdot V_s) / (4\pi \cdot \epsilon)]^{1/2}$	1	0.3	3.6	1.8	41.5	0.2
Huang HCAFOM, $\epsilon \mu^{0.5} E_C^2$	1	5	48	85	619	279

(010) homoepitaxy – published result (previous work)

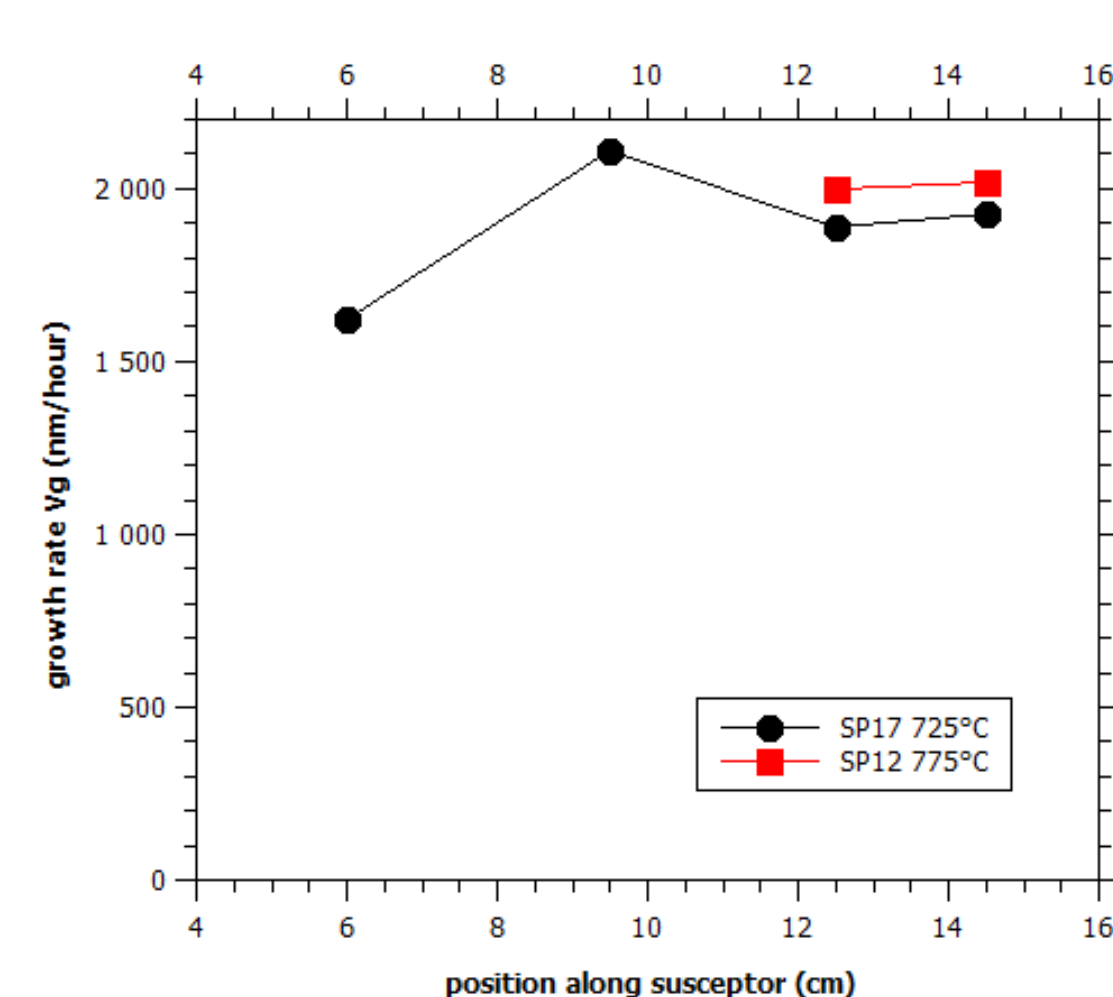
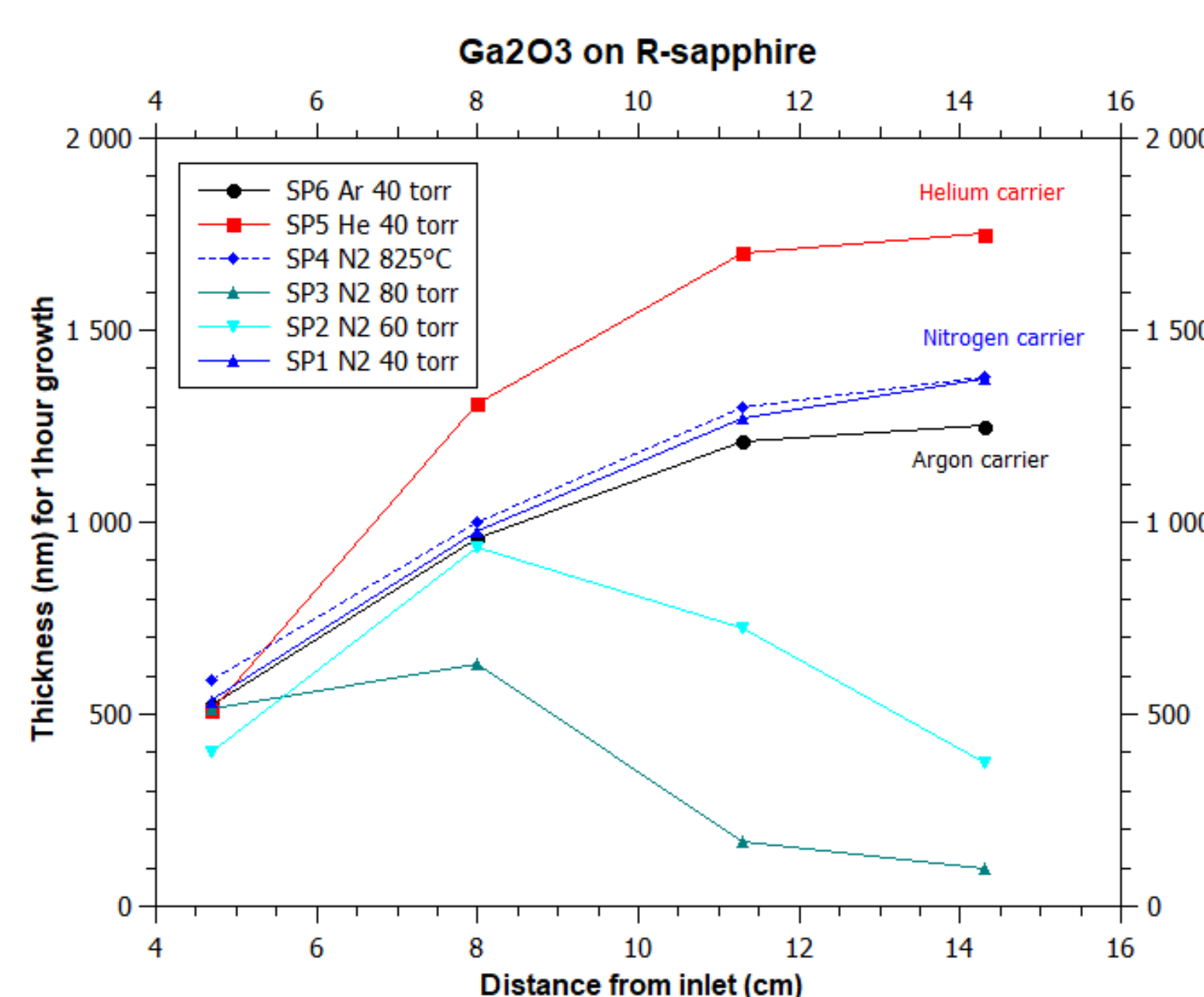
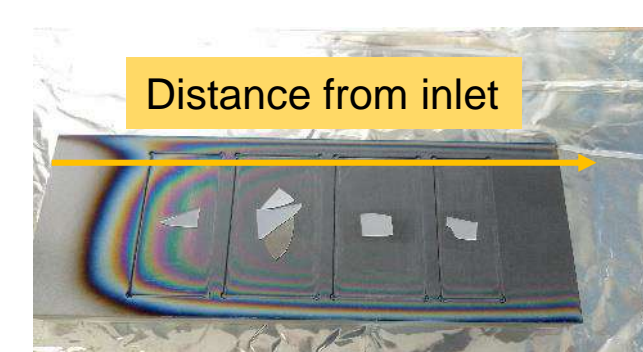
STEM : thanks to A. Perez, B. Mundet, B. Ballesteros, J. Santiso, Catalan Institute of Nanoscience and Nanotechnology (ICN2), CSIC, Barcelona Institute of Science and Technology (BIST), Barcelona, Spain



Homoepitaxial growth on (010) occurs without generation of extended defects or dislocations. For this (010) orientation, STEM was performed across [001] zone axis and we remark the occurrence of additional contrasts between two Ga1 atomic columns, as indicated by the blue arrow in the figure(d), which we attributed to columns of interstitial Ga, as suggested in ref. Bhuiyan et al, Appl. Phys. Lett. 115, 120602 (2019). Orange arrows indicate the expected locations of O atoms,

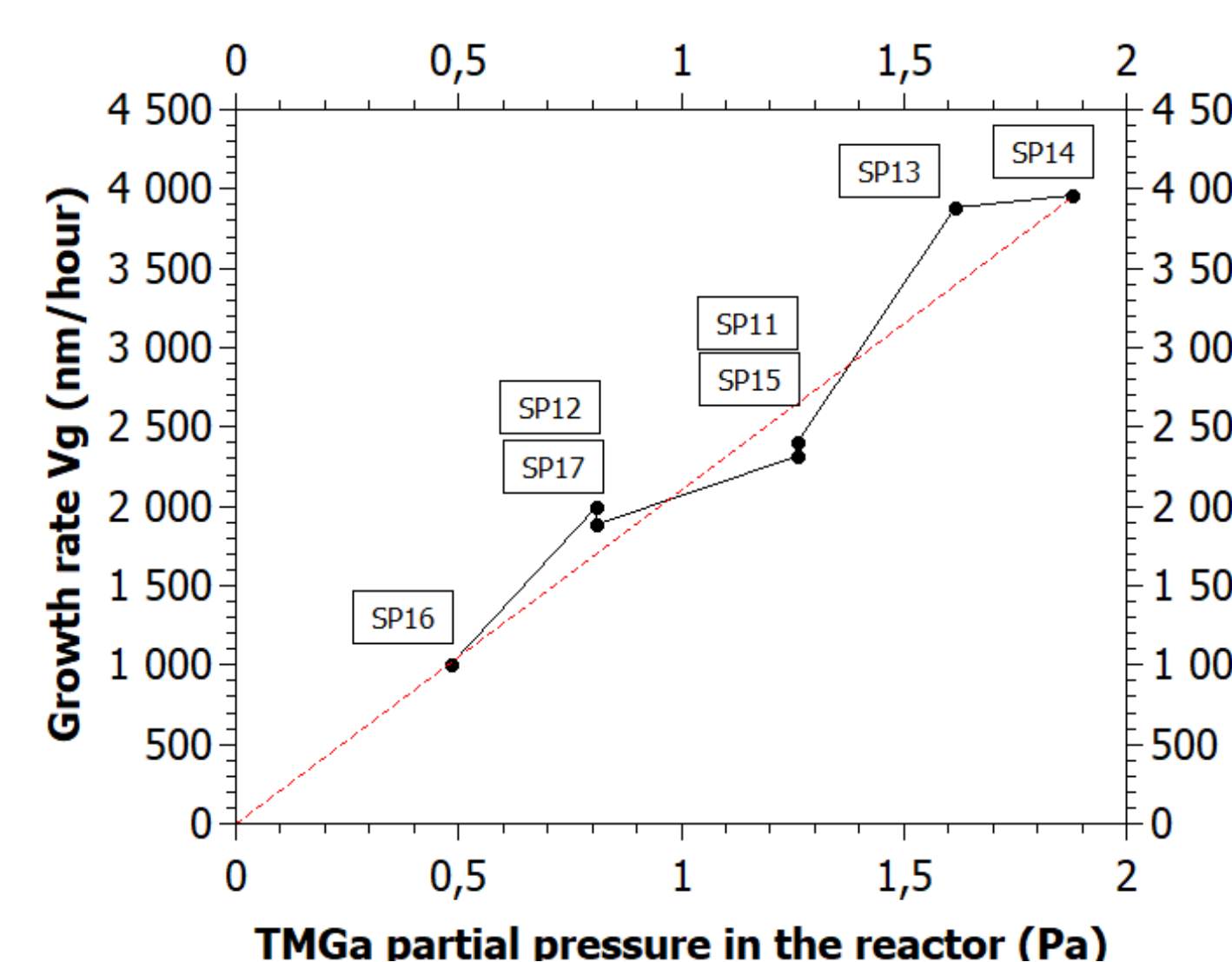
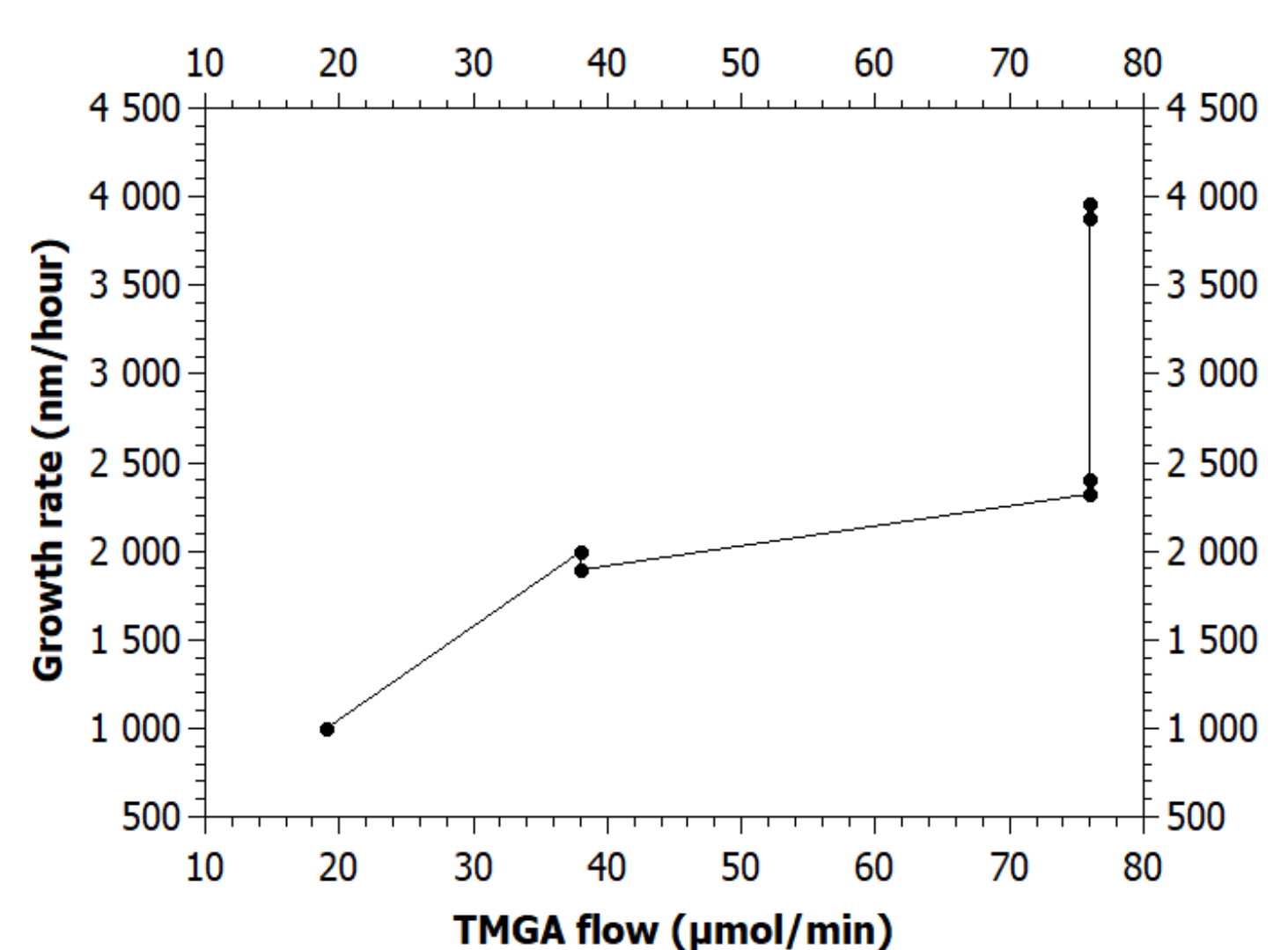
Growth rate studies

Ga₂O₃ layers on R-oriented sapphire



Variation with growth temperature T_g :
• no change in V_g between 725°C and 775°C

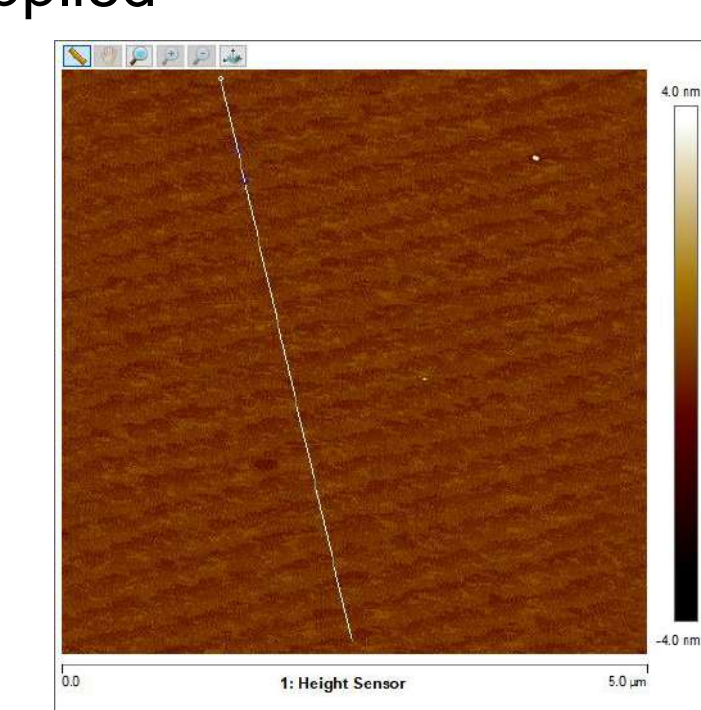
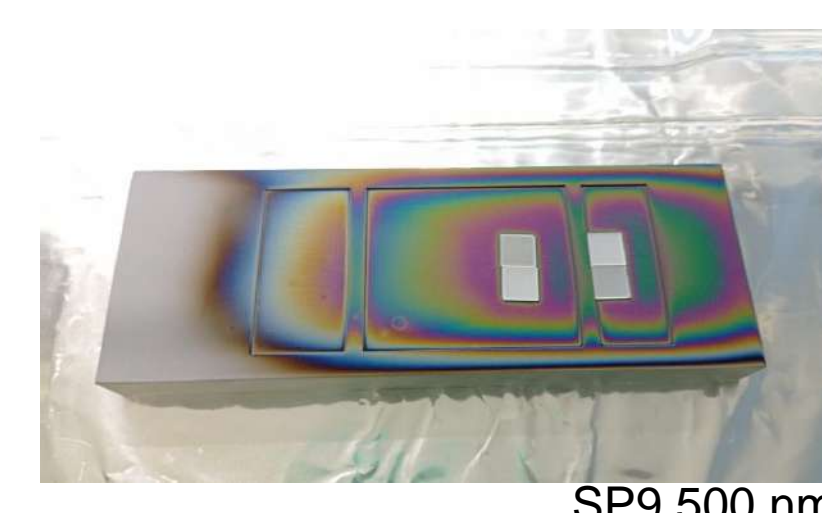
Growth rates are typically 2-3 μ m/h, and up to 4 μ m/h can be achieved



Since O₂ flows are high (750-3000 sccm), total flux is not constant and consequently the growth rate varies as a function of **TMGa partial pressure** (in Pa), and not TMGa flow (in μ mol/min)

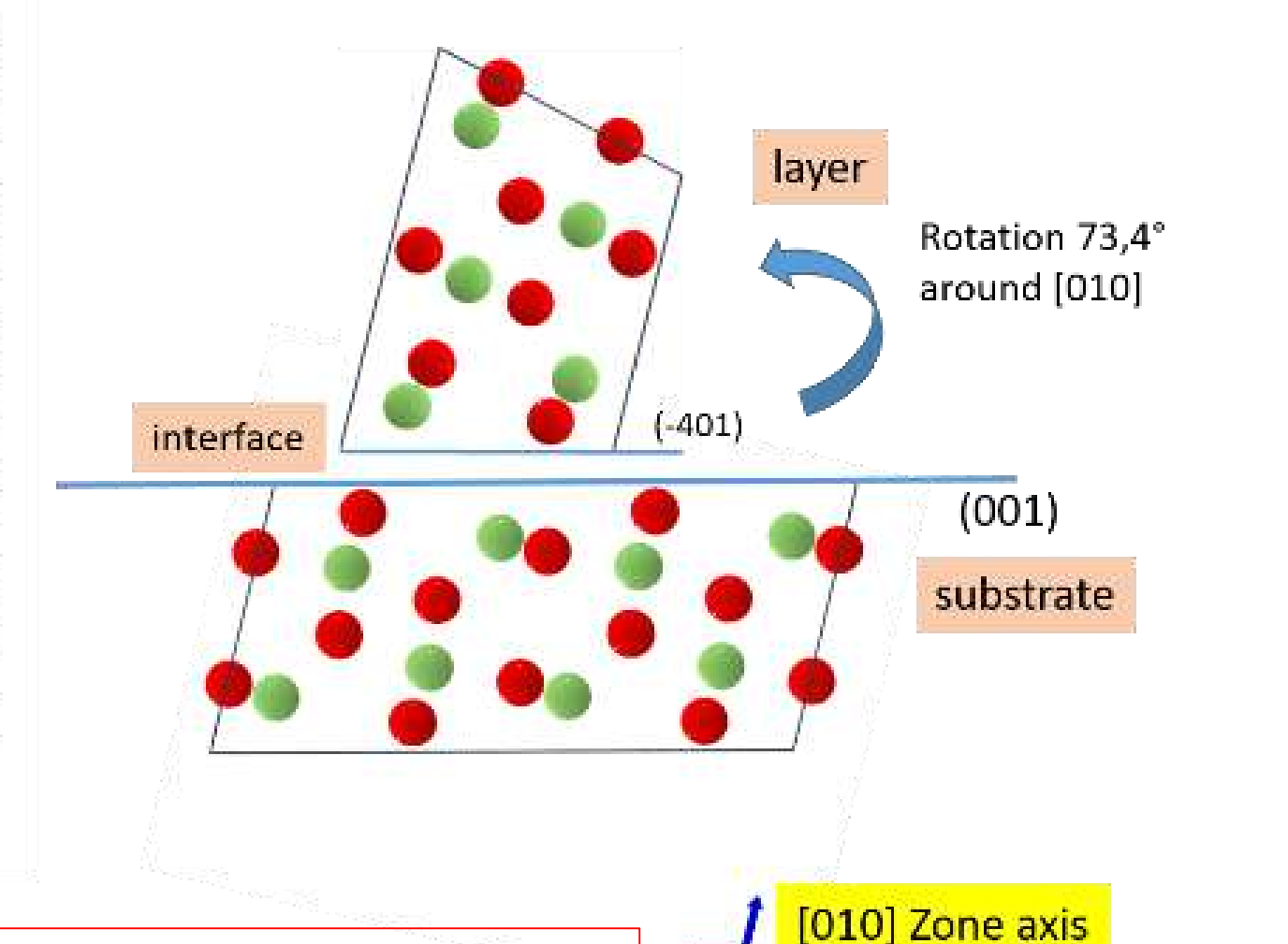
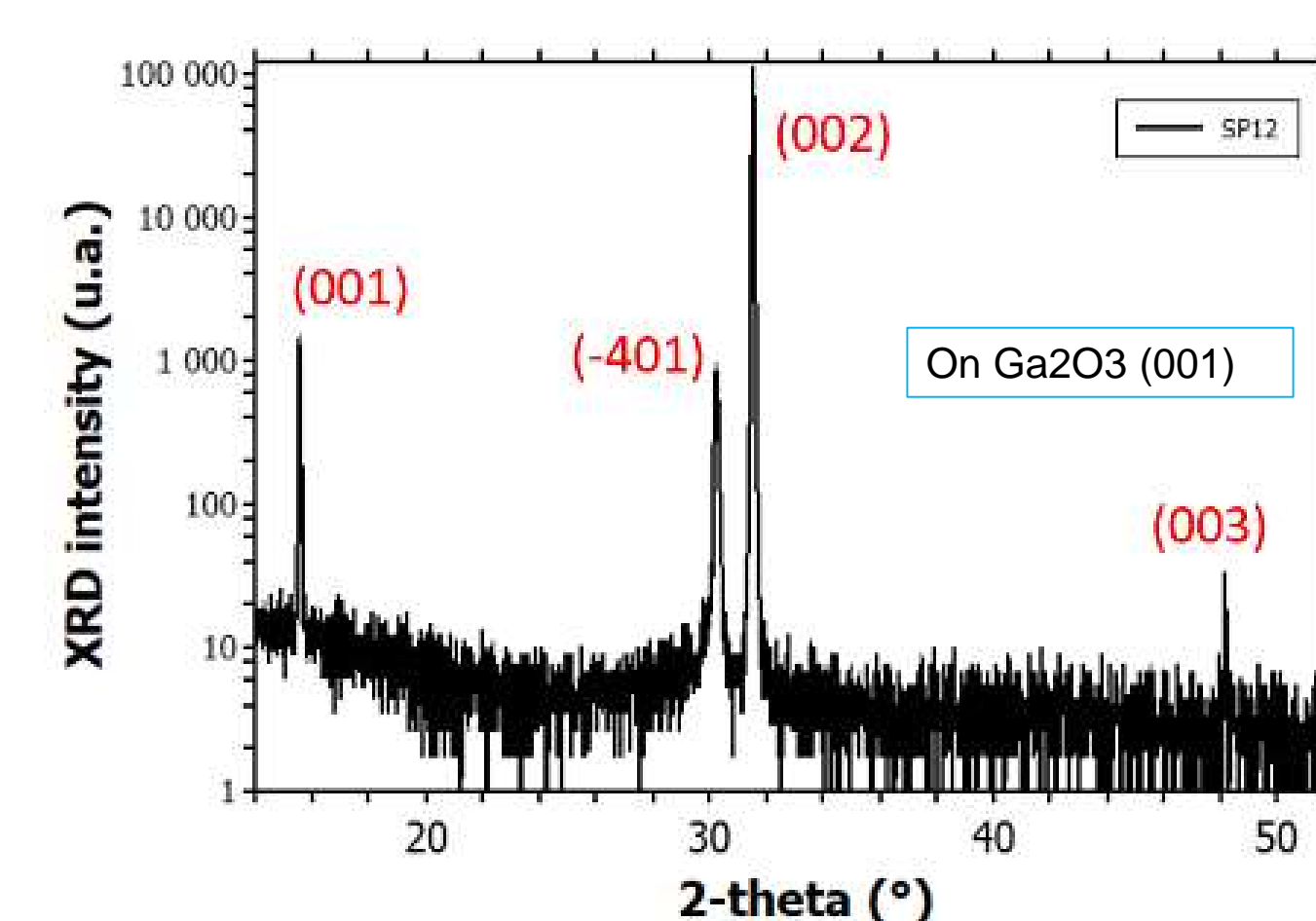
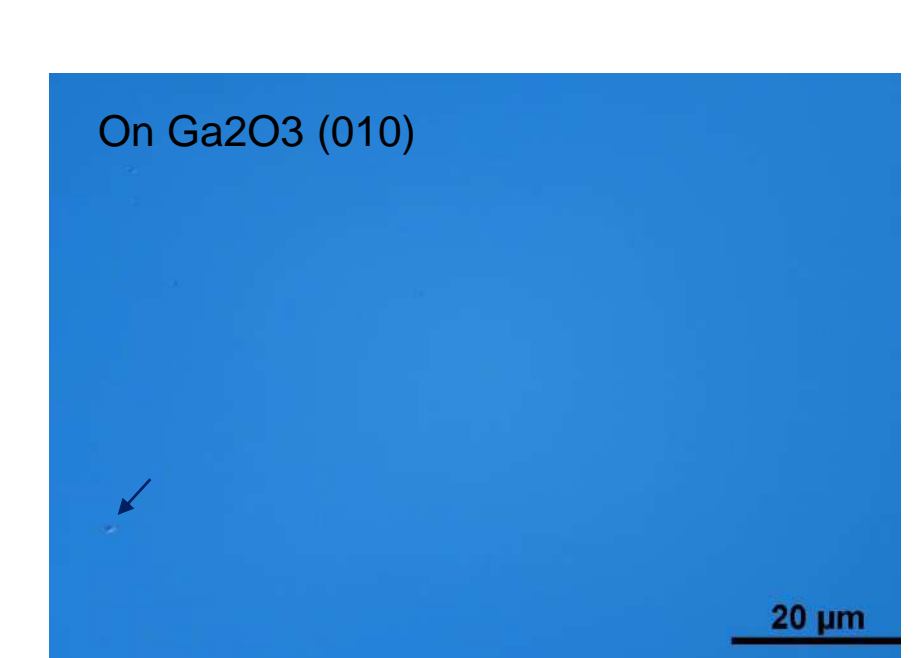
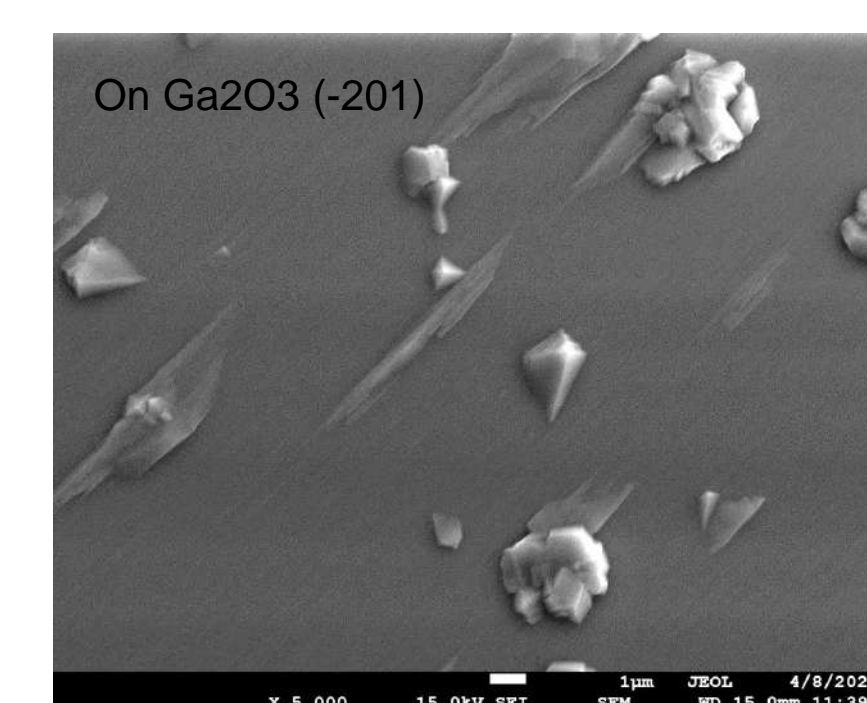
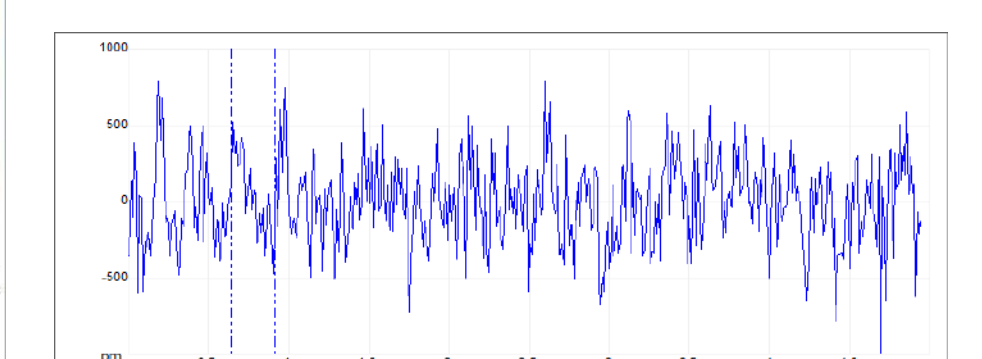
(-201) and (001) homoepitaxy

(001) Ga₂O₃ Sn doped substrate supplied by NCT (Japan), both sides polished



AFM image (Bruker ICON)

Ra = 0,215 nm



XRD spectra show a (-401) diffraction peak for almost all layers* grown on (001) substrates, corresponding to a rotation of 73,4° around [010] axis of, at least, a fraction of the grown material.
*except one sample grown with low O/Ga ratio, but contains carbon